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PATENT

Attorney Docket No. 211843-00032

**IN THE U.S. PATENT AND TRADEMARK OFFICE**

Application No.: 10/519,699  
I.A. Filing Date: June 26, 2003  
Inventor(s): Horsky, et al.  
Title: Ion Implantation Device and a Method of Semiconductor Manufacturing  
by the Implantation of Boron Hydride Cluster Ions  
Group Art Unit No.: 2881  
Confirmation No.: 6928

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**PRELIMINARY AMENDMENT**

Sir:

Prior to examining the instant application on the merits, please enter the following preliminary amendment.

**Amendment to the Specification is reflected on page 2.**

**Remarks begin on page 3 of this paper.**